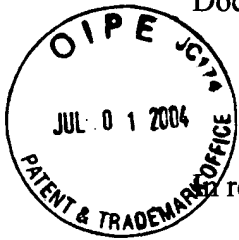


Docket No.: 50090-301

PATENT



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
BEFORE THE BOARD OF PATENT APPEALS AND INTERFERENCES

Re Application of

Toshihiro YAMASHITA, et al.

Serial No.: 09/901,038

Filed: July 10, 2001

Customer Number: 20277

Confirmation Number: 6404

Group Art Unit: 1763

Examiner: M. Crowell

For: PLASMA PROCESSING SYSTEM IN WHICH WAFER IS RETAINED BY
ELECTROSTATIC CHUCK, PLASMA PROCESSING METHOD AND METHOD OF
MANUFACTURING SEMICONDUCTOR DEVICE

NOTICE OF APPEAL
FROM THE PRIMARY EXAMINER
TO THE BOARD OF APPEALS

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Applicants hereby appeal to the Board of Appeals from the decision dated April 2, 2004 of
the Primary Examiner finally rejecting claims 1-7.

Appeal Fee: \$ 330.00

☐

Not required (fee paid in prior appeal in this application).

☒

Charge to Deposit Account No. 500417.

☐

Check Enclosed.

Respectfully submitted,

MCDERMOTT WILL & EMERY LLP

Scott D. Paul

Registration No. 42,984

07/02/2004 YPOLITE1 00000092 500417 09901038

01 FC:1401 330.00 DA

600 13th Street, N.W.
Washington, DC 20005-3096
(202) 756-8000 SDP:kap
Facsimile: (202) 756-8087
Date: July 1, 2004